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Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)		<b>Complete If Known</b>			
		Application Number	10/665,908-Conf. #7052		
		Filing Date	September 18, 2003		
		First Named Inventor	Demetrius Sarigiannis		
		Art Unit	1763		
		Examiner Name	Rudy Zervigon		
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U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
KMS		US-10/767,298	Filed 01-28-2004	Zheng et al.	
KMS		US-11/027,825	Filed 12-29-2004	Derderian et al.	
KMS		US-10/933,604	Filed 09-02-2004	Carpenter et al.	
KMS		US-10/687,458	Filed 10-15-2003	Kubista et al.	
KMS		US-10/683,424	Filed 10-10-2003	Mardian	
KMS		US-10/839,316	Filed 05-05-2004	Saragiannis et al.	
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KMS		US-11/043,629	Filed 01-25-2005	Rueger et al.	
KMS		US-11/018,142	Filed 12-20-2004	Rueger et al.	
KMS		US-10/840,571	Filed 05-06-2004	Dando et al.	
KMS		US-10/859,883	Filed 06-02-2004	Miller et al.	
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KMS		US-3,618,919	11-09-1971	Beck	
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KMS		US-3,630,881	12-28-1971	Lester et al.	
KMS		US-3,630,769	12-28-1971	Hart et al.	
KMS		US-3,634,212	01-11-1972	Valayll et al.	
KMS		US-4,018,949	04-19-1977	Donokowski et al.	
KMS		US-4,242,182	12-30-1980	Popescu	

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KMS	US-4,269,625	05-26-1981	Molenaar	
KMS	US-4,289,061	09-15-1981	Emmett	
KMS	US-4,397,753	08-09-1983	Czaja	
KMS	US-4,438,724	03-27-1984	Doehler et al.	
KMS	US-4,469,801	09-04-1984	Hirai et al.	
KMS	US-4,545,136	10-08-1985	Izu et al.	
KMS	US-4,590,042	05-20-1986	Drage	
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KMS	US-4,826,579	05-02-1989	Westfall	
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KMS	US-4,966,646	10-30-1990	Zdeblick	
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KMS	US-5,076,205	12-31-1991	Vowles et al.	
KMS	US-5,091,207	02-25-1992	Tanaka	
KMS	US-5,131,752	07-21-1992	Yu et al.	
KMS	US-5,136,975	08-11-1992	Bartholomew et al.	
KMS	US-5,172,849	12-22-1992	Barten et al.	
KMS	US-5,200,023	04-06-1993	Gifford et al.	
KMS	US-5,223,113	06-29-1993	Kaneko et al.	
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KMS	US-5,248,527	09-28-1993	Uchida et al.	
KMS	US-5,364,219	11-15-1994	Takahashi et al.	
KMS	US-5,377,429	01-03-1995	Sandhu et al.	
KMS	US-5,380,396	01-10-1995	Shikida et al.	
KMS	US-5,409,129	04-25-1995	Tsukada et al.	
KMS	US-5,418,180	05-23-1995	Brown	
KMS	US-5,427,666	06-27-1995	Mueller et al.	
KMS	US-5,433,835	07-18-1995	Demaray et al.	
KMS	US-5,445,491	08-29-1995	Nakagawa et al.	
KMS	US-5,480,818	01-02-1996	Matsumoto et al.	
KMS	US-5,498,292	03-12-1996	Ozaki	

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KMS	US-5,500,256	03-19-1996	Watabe	
KMS	US-5,522,934	06-04-1996	Suzuki et al.	
KMS	US-5,536,317	07-16-1996	Crain et al.	
KMS	US-5,562,800	10-08-1996	Kawamura	
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KMS	US-5,599,513	02-04-1997	Masaki et al.	
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KMS	US-5,693,288	12-02-1997	Nakamura	
KMS	US-5,729,896	03-24-1998	Dalal et al.	
KMS	US-5,746,434	05-05-1998	Boyd et al.	
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KMS	US-5,769,952	06-23-1998	Komino	
KMS	US-5,788,778	08-04-1998	Shang et al.	
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KMS	US-5,833,888	11-10-1998	Arya et al.	
KMS	US-5,846,330	12-08-1998	Quirk et al.	
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KMS	US-5,865,417	02-02-1999	Harris et al.	
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KMS	US-5,895,530	04-20-1999	Shrotriya et al.	
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KMS	US-5,932,286	08-03-1999	Beinglass et al.	

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KMS	US-5,953,634	09-14-1999	Kajita et al.	
KMS	US-5,956,613	09-21-1999	Zhao et al.	
KMS	US-5,968,587	10-19-1999	Frankel	
KMS	US-5,972,430	10-26-1999	DiMeo, Jr. et al.	
KMS	US-5,994,181	11-30-1999	Hsieh et al.	
KMS	US-5,997,588	12-07-1999	Goodwin et al.	
KMS	US-6,008,086	12-28-1999	Schuegraf et al.	
KMS	US-6,032,923	03-07-2000	Biegelsen et al.	
KMS	US-6,042,652	03-28-2000	Hyun et al.	
KMS	US-6,045,620	04-04-2000	Tepman et al.	
KMS	US-6,059,885	05-09-2000	Ohashi et al.	
KMS	US-6,062,256	05-16-2000	Miller et al.	
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KMS	US-6,079,426	06-27-2000	Subrahmanyam et al.	
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KMS	US-6,143,077	11-07-2000	Ikeda et al.	
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KMS	US-6,144,060	11-07-2000	Park et al.	
KMS	US-6,149,123	11-21-2000	Harris et al.	
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KMS	US-6,161,500	12-19-2000	Kopacz et al.	
KMS	US-6,174,366	01-16-2001	Ihantola	
KMS	US-6,174,377	01-16-2001	Doering et al.	
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KMS	US-6,178,660	01-30-2001	Emmi et al.	
KMS	US-6,182,603	02-02-2001	Shang et al.	
KMS	US-6,192,827	02-27-2001	Welch et al.	
KMS	US-6,194,628	02-27-2001	Pang et al.	
KMS	US-6,193,802	02-27-2001	Pang et al.	
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KMS	US-6,200,415	03-13-2001	Maraschin	
KMS	US-6,203,613	03-20-2001	Gates et al.	
KMS	US-6,206,972	03-27-2001	Dunham	
KMS	US-6,211,078	04-03-2001	Matthews	
KMS	US-6,211,033	04-03-2001	Sandhu et al.	
KMS	US-6,210,754	04-03-2001	Lu et al.	
KMS	US-6,214,714	04-10-2001	Wang et al.	
KMS	US-6,237,394	05-29-2001	Harris et al.	
KMS	US-6,237,529	05-29-2001	Spahn	
KMS	US-6,245,192	06-12-2001	Dhindsa et al.	
KMS	US-6,255,222	07-03-2001	Xia et al.	
KMS	US-6,263,829	07-24-2001	Schneider et al.	
KMS	US-2001/0010309-A1	08-02-2001	Van Bilsen	
KMS	US-6,270,572	08-07-2001	Kim et al.	
KMS	US-2001/0011526-A1	08-09-2001	Doering et al.	
KMS	US-6,280,584	08-28-2001	Kumar et al.	
KMS	US-6,287,980	09-11-2001	Hanazaki et al.	
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KMS	US-6,291,337	09-18-2001	Sidhwa	
KMS	US-6,290,491	09-18-2001	Shahvandi et al.	
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KMS	US-6,297,539	10-02-2001	Ma et al.	
KMS	US-6,302,964	10-16-2001	Umotoy et al.	
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KMS	US-2001/0045187-A1	11-29-2001	Uhlenbrock	
KMS	US-6,329,297	12-11-2001	Ballsh et al.	
KMS	US-2001/0054484-A1	12-27-2001	Komino	
KMS	US-2002/0007790-A1	01-24-2002	Park	
KMS	US-6,342,277	01-29-2002	Sherman	
KMS	US-6,346,477	02-12-2002	Kaloyeros et al.	
KMS	US-6,347,602	02-19-2002	Goto et al.	
KMS	US-6,347,918	02-19-2002	Blahnik	
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KMS	US-6,355,561	03-12-2002	Sandhu et al.	
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KMS	US-6,387,185	05-14-2002	Doering et al.	
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KMS	US-2002/0094689-A1	07-18-2002	Park	
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KMS	US-6,428,859	08-06-2002	Chiang et al.	
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KMS		US-6,450,117	09-17-2002	Murugesh et al.	
KMS		US-6,451,119	09-17-2002	Sneh et al.	
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KMS		US-6,458,416	10-01-2002	Derderian et al.	
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KMS		US-2002/0164420-A1	11-07-2002	Derderian et al.	
KMS		US-2002/0162506-A1	11-07-2002	Sneh et al.	
KMS		US-2002/0185067-A1	12-12-2002	Upham	
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KMS		US-2003/0003730-A1	01-02-2003	Li	
KMS		US-2003/0000473-A1	01-02-2003	Chae et al.	
KMS		US-2003/0003697-A1	01-02-2003	Agarwal et al.	
KMS		US-6,503,330	01-07-2003	Sneh et al.	
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KMS		US-2003/0013320-A1	01-16-2003	Kim et al.	
KMS		US-6,509,280	01-21-2003	Choi	
KMS		US-2003/0023338-A1	01-30-2003	Chin et al.	
KMS		US-2003/0024477-A1	02-06-2003	Okuda et al.	
KMS		US-2003/0027428-A1	02-06-2003	Ng et al.	
KMS		US-2003/0027431-A1	02-06-2003	Sneh et al.	

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KMS		US-2003/0037729-A1	02-27-2003	DeDontney et al.	
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KMS		US-6,534,007	03-18-2003	Blonigan et al.	
KMS		US-2003/0060030-A1	03-27-2003	Lee et al.	
KMS		US-6,540,838	04-01-2003	Sneh et al.	
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KMS		US-2003/0066483-A1	04-10-2003	Lee et al.	
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KMS		US-6,562,141	05-13-2003	Clarke	
KMS		US-2003/0098372-A1	05-29-2003	Kim	
KMS		US-2003/0098419-A1	05-29-2003	Ji et al.	
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KMS		US-6,638,672	10-28-2003	Deguchi	

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				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
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